

CDE ResMap 463-OC

Designed to meet the needs of 300mm high volume manufacturing, the ResMap Model 463-OC features CDE's patented multiple probe changer - available in either the two or four probe configuration. This unique capability delivers the most cost effective four point probe for conductive film measurements. This model is capable of handling 300mm, 200mm and 150mm wafers in open cassettes.

Specification			
Features:	300mm, 200mm, 150mm; dual or quad probe changer	Minimum Edge Exclusion:	1.5mm (center of probe to edge of film)
Wafer Size:	300mm, 200mm, 150mm auto load; manual load any size	Computer System:	Pentium class 1.2 GHz, 512MB RAM, 40GB HD, DVD-RW, FD; 15" monitor; operating system: Windows XP
Max Diameter:	15"	SECS-II Option:	Available; 300mm factory automation also available
Max Square:	10.5" x 10.5"	POD-ID Option:	N/A
Typical Measurement Time:	1 second per site	Mapping Patterns:	Polar map (align with notch/flat, straddle, or follow flat); rectangular map (choose inside edge exclusion); line scan (diameter, radius or any point to point along diameter, minimum step 0.1mm); user defined (template)
Typical Wafer Handling Time:	8 seconds each way	Plots:	Contour (spacing choice, 1/3 σ , fixed and auto %), 3D, line, data map, histogram, data sequence, radial and angular distributions; various modes of trend charts available
Typical Notch Find Time:	12 seconds; standard notch finder	Data:	All ResMap data files can be ported to programs such as Excel® for further analysis.
Maximum Throughput:	45 wph without NF; 30 wph with NF (49 sites)	Facilities	
Measurement Range:	2 mΩ/ \square - 5 MΩ/ \square (can be optimized to 1 mΩ/ \square)	House Vacuum :	Required; >500 mm Hg, on ¼" OD flexible tubing
Repeatability (1σ):	$\leq \pm 0.02\%$ (static or Rs pack); $\leq \pm 0.1\%$ (dynamic nearby spots, typical)	AC Power:	100V to 240V < 10 KVA
Accuracy:	≤±0.5% using NIST traceable ResCal standards	Size (inches): width x depth x height	22"w x 44"d x 52"h; stand alone (computer system, etc. enclosed)